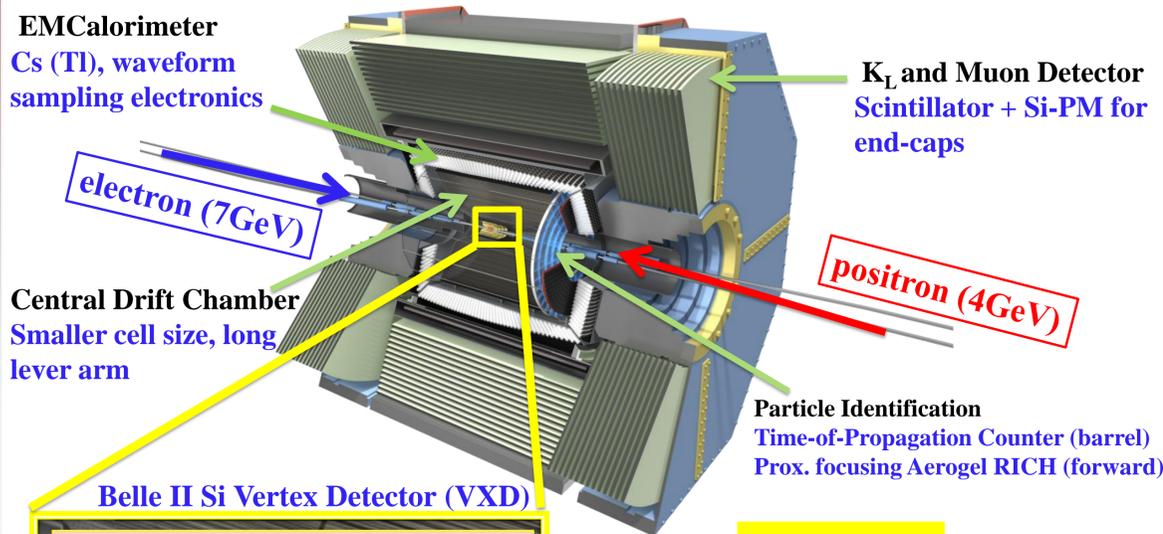


Physics Motivation

- The silicon vertex detector (SVD) is one of the important sub-detectors of the Belle II experiment at SuperKEKB.
- It consists of four-layers of double-sided silicon strip detectors (DSSDs).
- It plays a key role in the precise measurement of the decay vertex and reconstruction of the low-momentum tracks along with the pixel detector (PXD).
- The excellent performance of the Belle II SVD will provide the measurements of CP asymmetry in the B-meson system with higher precision.
- To achieve the physics goals, reconstruction of tracks with a high efficiency and a good resolution is needed.
- Design luminosity of SuperKEKB: $8 \times 10^{35} \text{ cm}^{-2} \text{ s}^{-1}$ that would enable Belle II to collect 50 ab^{-1} of data, 50 times more than its predecessor (Belle).
- Leads to harsh background environment in the Belle II.
- To validate the performance of the SVD, a systematic study is needed in the offline software reconstruction environment.

Belle II Detector

Design luminosity = $8 \times 10^{35} \text{ cm}^{-2} \text{ s}^{-1}$
 $e^+ (4 \text{ GeV}) + e^- (7 \text{ GeV}) \rightarrow B\bar{B}$ at $\sqrt{s} = 10.58 \text{ GeV}$ [at $\Upsilon(4S)$]

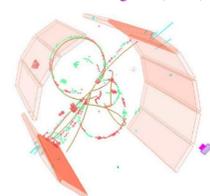


Current Status

The Belle II operation in Phase 2

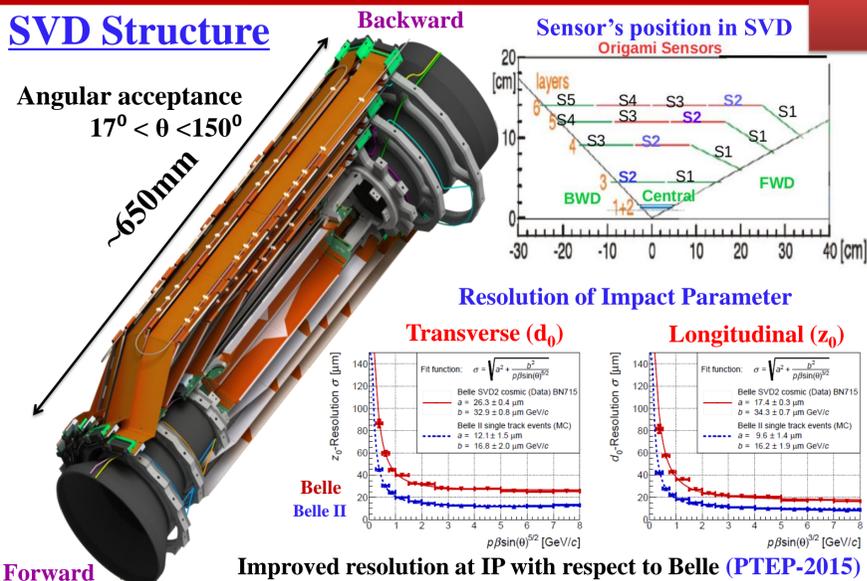
- A subset of the vertex detector, comprising six layers with a single ladder per layer, installed since Spring 2018 (Phase 2) successfully joining Belle II first data taking.
- Belle II operation with the full VXD will start in Spring 2019 (Phase 3)

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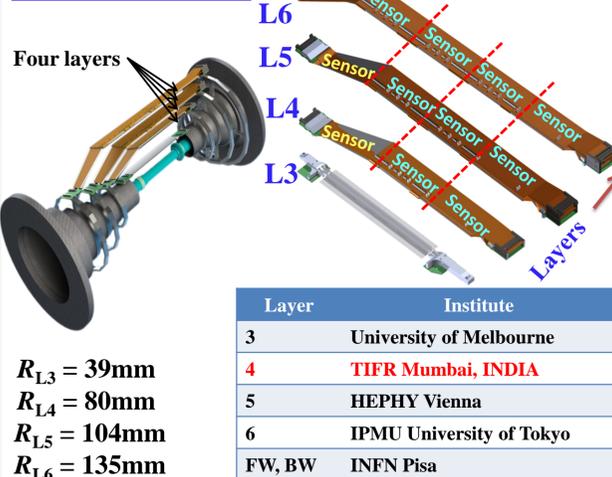
First Phase 2 collision events recorded by Belle II.

SVD Structure



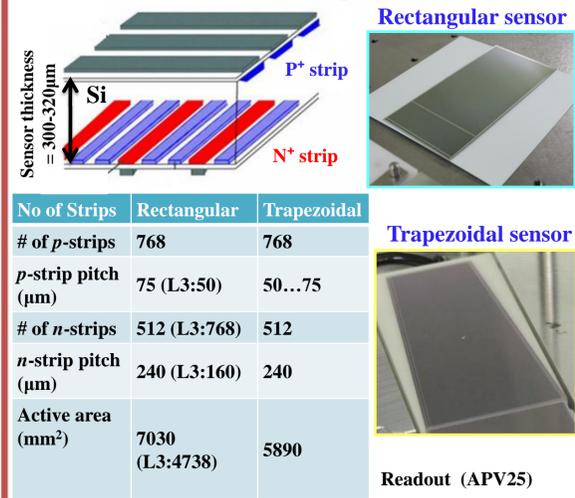
Belle II Silicon Vertex Detector

SVD Ladders



SVD Sensors

Double Sided Si Strip Detector (DSSD)



Test Beam Data (2017)

(DESY, Germany)

Set-up: 4 GeV electron beam
 4 SVD layers + 2 PXD layers in 1T magnetic field

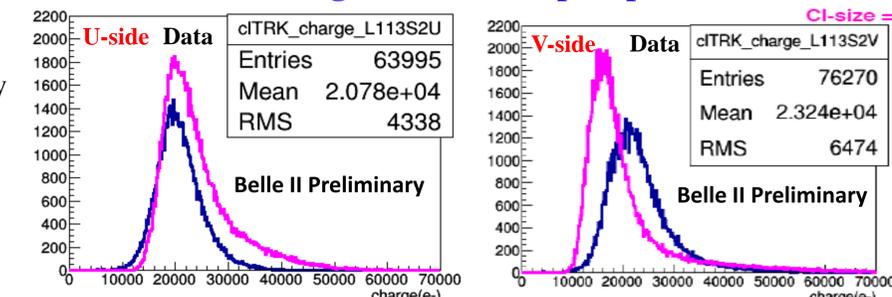
- In Belle II SVD, charge loss is significant in sensors with large pitch, as the back-side capacitance increases linearly with the implant pitch.
- This sensitivity of the cluster charge to the interstrip capacitance (C_{int}) can be exploited:
- To measure the actual interstrip capacitance of SVD sensors.
- Tune this important input parameter for the full SVD simulation.

For this measurement, comparison of test beam data and the full SVD simulation is needed.

- Cluster charge as a function of the interstrip capacitance is evaluated with the full SVD simulation, for the various cluster widths and compared to data to measure the C_{int} .

Monte Carlo Simulation and Data Analysis

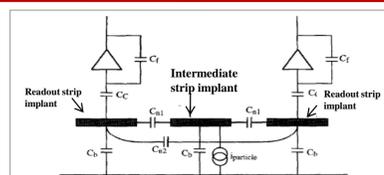
Cluster Charge and Interstrip Capacitance



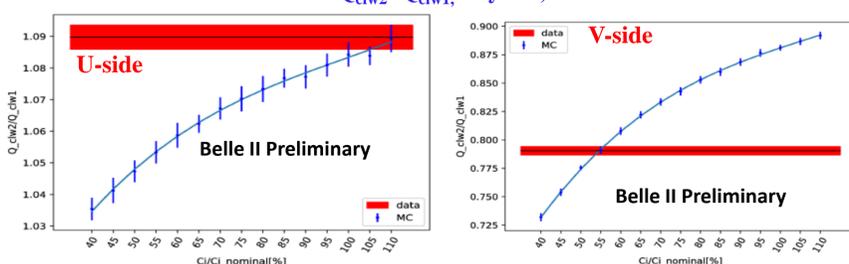
$$\text{Ratio } R = \frac{Q_{clw2}}{Q_{clw1}}$$

Q_{clw2} charge for clw2
 Q_{clw1} charge for clw1

clw: cluster width
 M. Kramer, H. Pernegger, NIMA 397 (1997) 232
 Events: 1M (MC), ~700k (data)



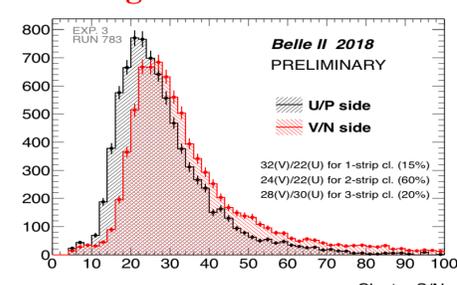
Results of Q_{clw2}/Q_{clw1} , Layer 3, Sensor 2



First Data (2018)

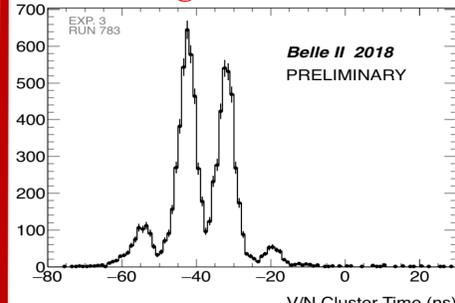
(KEK, Japan)

Signal to Noise Ratio



S/N greater than 20, with the N side performing slightly better than the P side, as expected.

Signal Hit Time



The RMS of cluster times corresponding to a bunch crossing is in the order of 3 ns, nicely matching the design.

Summary

- Effect of the interstrip capacitance (C_{int}) on the cluster charge is studied in test beam data and compared with simulations to measure C_{int} for the different SVD layers/sensors.
- Measured S/N ratio on the first data with tracks of different momentum and inclination matches the design expectations.
- With first data, it is demonstrated that the SVD is clearly able to distinguish bunch crossings of 16 ns apart.